

Derek R Oliver

List of Publications by Year in descending order

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citing authors

#	ARTICLE	IF	CITATIONS
1	An interpretable CNN model for classification of partial discharge waveforms in 3D-printed dielectric samples with different void sizes. <i>Neural Computing and Applications</i> , 2022, 34, 11739-11750.	5.6	7
2	Sensitivity analysis of a parallel-plate method for measuring the dielectric permittivity of high-voltage insulating materials. <i>High Voltage</i> , 2017, 2, 200-204.	4.7	6
3	Monohydride signature as a key predictor of successful Si(110) surface functionalization. <i>RSC Advances</i> , 2016, 6, 88239-88243.	3.6	2
4	Direct contact four-point probe characterization of Si microwire absorbers for artificial photosynthesis. <i>RSC Advances</i> , 2016, 6, 110344-110348.	3.6	2
5	Correlation of microscopic textural features and degree of polymerization for thermally deteriorated cellulose insulation. , 2016, . .		1
6	Classification of degradation in oil-impregnated cellulose insulation using texture analysis of optical microscopy images. <i>Electric Power Systems Research</i> , 2016, 133, 104-112.	3.6	9
7	Electrical Characteristics of the Junction between PEDOT:PSS and Thiophene-Functionalized Silicon Microwires. <i>ACS Applied Materials & Interfaces</i> , 2015, 7, 27160-27166.	8.0	18
8	Piezoresistive characterization of bottom-up, n-type silicon microwires undergoing bend deformation. <i>Applied Physics Letters</i> , 2015, 106, 022107.	3.3	10
9	Measurement of the Electrical Resistance of n-Type Si Microwire/p-Type Conducting Polymer Junctions for Use in Artificial Photosynthesis. <i>Journal of Physical Chemistry C</i> , 2014, 118, 27742-27748.	3.1	9
10	Comparison between the electrical junction properties of H-terminated and methyl-terminated individual Si microwire/polymer assemblies for photoelectrochemical fuel production. <i>Energy and Environmental Science</i> , 2012, 5, 9789.	30.8	18
11	Characterization of the Electrical Properties of Individual p-Si Microwire/Polymer/n-Si Microwire Assemblies. <i>Journal of Physical Chemistry C</i> , 2011, 115, 24945-24950.	3.1	15
12	Electrical Characterization of Si Microwires and of Si Microwire/Conducting Polymer Composite Junctions. <i>Journal of Physical Chemistry Letters</i> , 2011, 2, 675-680.	4.6	17
13	A Circular Patch Resonator for the Measurement of Microwave Permittivity of Nematic Liquid Crystal. <i>IEEE Transactions on Microwave Theory and Techniques</i> , 2011, 59, 1855-1862.	4.6	30
14	A Spectral Transmission-Line Method for Computing Band Diagrams and Eigenmodes of Photonic-Bandgap Structures. <i>IEEE Transactions on Microwave Theory and Techniques</i> , 2009, 57, 627-636.	4.6	2
15	Rapid Simulation of Linear PBG Microstrip Structures Using the Rayleigh Multipole Method. <i>IEEE Transactions on Microwave Theory and Techniques</i> , 2008, 56, 49-55.	4.6	12
16	Microelectromechanical Resonator Characterization Using Noncontact Parametric Electrostatic Excitation and Probing. <i>Journal of Microelectromechanical Systems</i> , 2007, 16, 1054-1060.	2.5	11
17	Electronic transport in dielectrophoretically grown nanowires. <i>Journal of Materials Science</i> , 2006, 41, 8166-8172.	3.7	5
18	Capacitance sensor with sub-zeptofarad ($<10^{21}$ F) sensitivity for scanning capacitance microscopy. <i>Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena</i> , 2002, 20, 479.	1.6	9

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19	â€œZeptofaradâ€ (10 ⁻²¹ F) resolution capacitance sensor for scanning capacitance microscopy. Review of Scientific Instruments, 2001, 72, 2618-2623.	1.3	38
20	Heterodyne electrostatic imaging of polarization due to a surface acoustic wave. Applied Physics Letters, 2001, 79, 3729-3731.	3.3	4
21	Quantitative two-dimensional carrier profiling of a 400 nm complementary metalâ€oxideâ€semiconductor device by Schottky scanning capacitance microscopy. Journal of Applied Physics, 2000, 88, 6752-6757.	2.5	9